



Designed to measure aspherical lenses & molds, semiconductor wafers, and any other precision component requiring nanometer level accuracy

Ultrahigh accurate 3-D profilometer (UA3P)

The Panasonic UA3P profilometer series is designed to measure aspherical lenses & molds, semiconductor wafers, and any other precision component requiring nanometer level accuracy ranging up to 200mm x 200mm. Different machine models are available to meet your optical & high aspect ratio metrology needs. The UA3P-300, UA3P-4 and UA3P-5 all offer users the accuracy of AFM technology with the measurement range of a CMM. Our unique approach uses atomic force probe technology in the stylus and HeNe laser-based interferometric XYZ axis positioning. Couple this technology with a solid granite-base and you have a robust metrology system that can be used on the factory floor and still deliver 0.1um level total uncertainty.

Key Features

Ultra-accurate measurement in only 3 minutes

Automatic NC program generation

Extensive library of optional software

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<https://ap.connect.panasonic.com/my/en/products/smart-factory/ultrahigh-accurate-3-d-profilometer-ua3p>